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Inventor.....J. Kim  
Assignee.....Honeywell International Inc.  
Group Art Unit..... unknown  
Examiner ..... unknown  
Attorney's Docket No. ....H0006155 USA  
Customer No. ....021567  
Title: Methods Of Treating Deposition Process Components To Form Particle Traps, And  
Deposition Process Components Having Particle Traps Thereon

**PRELIMINARY AMENDMENT**

To: Commissioner for Patents  
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**AMENDMENTS**